

7/12/02
#5Amdt
Attachment

503.28546CV9



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: TORII, et al.
Serial No.: 09/917,912
Filed: July 31, 2001
For: METHOD AND APPARATUS FOR PROCESSING
SAMPLES
Group: 1756
Examiner: M. Angebranndt

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AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

July 15, 2002

Sir:

In response to the Office Action mailed February 14, 2002, please amend the above-identified application as follows:

IN THE CLAIMS

Please cancel claims 1-7, 18-26 and 28-65 without prejudice or disclaimer, and amend the claims remaining in the application as follows:

SUB
8.1

8. (Twice Amended) A method of processing a semiconductor sample having a laminate comprising at least two adjacent films of at least two different metals of different ionization tendencies overlying a semiconductor substrate, whereby corrosion could be generated and accelerated due to battery action between films of the laminate, including said at least two adjacent films, comprising